	Application No.	Applicant(s)
Notice of Allowability	10/736,720	LEE, KEUN WOO
	Examiner	Art Unit
	Eric B. Chen	1765
The MAILING DATE of this communication appears on the cover sheet with the correspondence address All claims being allowable, PROSECUTION ON THE MERITS IS (OR REMAINS) CLOSED in this application. If not included herewith (or previously mailed), a Notice of Allowance (PTOL-85) or other appropriate communication will be mailed in due course. THIS NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RIGHTS. This application is subject to withdrawal from issue at the initiative of the Office or upon petition by the applicant. See 37 CFR 1.313 and MPEP 1308.		
1. This communication is responsive to <u>7 November 2005</u> .		
2. The allowed claim(s) is/are <u>6-9</u> .		
3.		
Attachment(s)  1. Notice of References Cited (PTO-892)  2. Notice of Professoria Retail Proving Review (PTO 048)		atent Application (PTO-152)
2. Notice of Draftperson's Patent Drawing Review (PTO-948)	6. ☐ Interview Summary Paper No./Mail Dat	e
<ol> <li>Information Disclosure Statements (PTO-1449 or PTO/SB/0 Paper No./Mail Date</li> </ol>	8), 7. Examiner's Amendo	nent/Comment
4. Examiner's Comment Regarding Requirement for Deposit of Biological Material	8. X Examiner's Stateme	ent of Reasons for Allowance
	9.  Other	

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## **REASONS FOR ALLOWANCE**

1. Claims 6-9 are allowed.

2. The following is an examiner's statement of reasons for allowance: the prior art fails to teach or suggest forming a nitride film on an entire surface of the trench; and forming a side wall silicon oxide film on a surface of the nitride film and a sidewall of the polysilicon film (emphasis added). The closest prior art, Kunikiyo, discloses forming a nitride film (6) only on the upper region of the trench (column 15, lines 30-36; Figure 6). Moreover, silicon oxide film (8) directly contacts semiconductor substrate (1) (column 16, lines 16-23; Figure 7), but does not contact polysilicon film (3) (Figure 7). However, there is no motivation or suggestion of forming a nitride film on an entire surface of the trench; and forming a side wall silicon oxide film on a surface of the nitride film and a sidewall of the polysilicon film, as in the context of claim 6.

3. Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

## Response to Arguments

4. In view of Applicant's amendments to claim 6, filed Nov. 7, 2005, the claim objection and the rejection under 35 U.S.C. 112, second paragraph, as being indefinite, has been withdrawn.

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5. Applicant's arguments (Applicant's Remarks, pages 6-7), filed Nov. 7, 2005, with respect to the rejection of claims 6-9 under 35 U.S.C. 103(a) have been fully considered and are persuasive. The Kunikiyo reference does not teach or suggest the newly added claim limitations to claim 6 of "forming a nitride film on an entire surface of the trench" and "forming a side wall silicon oxide film on a surface of the nitride film and a sidewall of the polysilicon film." The rejection of claims 6-9 has been withdrawn.

## Conclusion

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Eric B. Chen whose telephone number is (571) 272-2947. The examiner can normally be reached on Monday through Friday, 8AM to 4:30PM.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Nadine G. Norton can be reached on (571) 272-1465. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

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**EBC** 

Dec. 5, 2005

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